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Fabrication of High Quality Topological Insulator Thin Films and Heterostructures LI ZHANG, ROBERT HAMMOND, MERAV DOLEV, MAC BEASLEY, AHARON KAPITULNIK, Stanford University, GLAM TEAM — In this talk, I will present a method of fabrication high quality topological insulator thin films and heterostructures with ferromagnet materials using MBE with a RF Selenium cracker cell and pulsed laser deposition. I will also show some preliminary results on the physical properties of those films, including topography, crystal structure and transport properties.

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